# LiNbO<sub>3</sub>/Si-Hybrid Slot-Waveguide Electro-Optic Modulators

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Abstract—A new LiNbO $_3$ /Si-hybrid electro-optic modulator that utilizes a doped-Si slot waveguide is proposed. An excellent performance, i.e., an improvement of two orders of magnitude in  $V_\pi L$ , is demonstrated via simulations when compared with the performance of the conventional LiNbO $_3$  modulators.

Keywords—Electro-optic modulator, LiNbO<sub>3</sub>, Si, Simulation, Slot waveguide

### I. INTRODUCTION

S I photonics is revolutionizing the short-reach transceivers in data centers [1], while legacy LiNbO<sub>3</sub> optical modulators are still dominating for the long-distance optical communications. The advantages of Si optical modulators are availabilities of low-cost fabrication processes, low-power consumption, and integration capabilities with various optical Si components, while the disadvantages are the operation speed typically up to 40-50Gbps and absence of intrinsic electro-optic (E/O) effect for low-optical-loss operation. Although the conventional LiNbO<sub>3</sub> optical modulators have advantages of strong E/O effect without carrier injections, high-speed operation exceeding 100Gbps, and high reliability over other materials, e.g., organic polymers [2], they have disadvantages of lack of patterning processes [3], large feature size (as large as ~50mm in length), large power consumption due to  $50-\Omega$  termination for the travelling-waveguide electrodes, and difficulties of integration.

Here, we report an excellent modulator performance using a type of  $LiNbO_3/Si$ -hybrid E/O modulator, as shown in Fig. 1, by overcoming those drawbacks of the conventional  $LiNbO_3$  modulator with the help of the Si technology.

## II. DEVICE STRUCTURE AND FUNCTION

In the proposed hybrid modulator, doped-Si on top of a silicon-on-insulator (SOI) wafer is patterned into

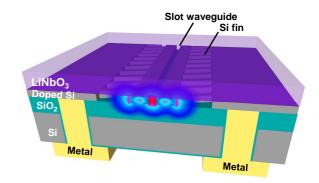


Fig. 1 LiNbO<sub>3</sub>/Si-hybrid electro-optic modulator. The doped-Si slot waveguide is sandwiched between LiNbO<sub>3</sub> and SiO<sub>2</sub> layers.

the slot waveguide, and pristine LiNbO3 is bonded onto it (e.g., via the direct-wafer-bonding technique), thus avoiding the difficulties in patterning on LiNbO<sub>3</sub>. Here we use an evanescent mode [4] formed between the doped-Si slot waveguide and the attached LiNbO<sub>3</sub>, which gives a small optical core size (or high optical intensity) in LiNbO<sub>3</sub>. The doped-Si slot waveguide also works as electrodes, which give high electric field to LiNbO<sub>3</sub> with small-gapped electrodes. Those features make it possible to remarkably downsize the LiNbO<sub>3</sub> modulator of length  $\sim$ 50mm and core size 3-10 $\mu$ m, thus achieving low-power consumption by removal of the  $50-\Omega$  termination resistor and use of lumped constant circuits. Furthermore, if we can reduce the operation voltage down to 1V with the small-gapped electrodes, we can use a CMOS driver.

Employing the doped-Si slot waveguide with the above excellent properties, our new LiNbO<sub>3</sub>/Si-hybrid modulator realizes a remarkable improvement in modulator performance (i.e., two orders of magnitude small  $V_{\pi}L$ ) when compared with the performance of the conventional LiNbO<sub>3</sub> modulator ( $V_{\pi}L \sim 10 \text{V} \cdot \text{cm}$  [5]), which will be shown in detail in the next section.

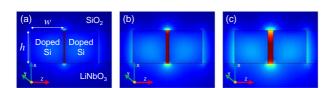


Fig. 2 Optical field of the doped-Si slot waveguide on LiNbO<sub>3</sub> at an input wavelength of 1550nm for TE-modes with different slot air-gap sizes: (a) 10 nm, (b) 30 nm, (c) 50 nm. The colors (blue, yellow, red) of the field strength represent 0, 80, 140V/m, respectively.

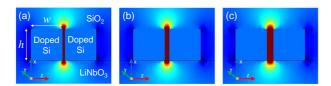


Fig. 3 Electric field  $(E_z)$  of the horizontal (z) direction for the slot waveguide on LiNbO<sub>3</sub> with different slot air-gap sizes: (a) 20 nm, (b) 40 nm, (c) 60 nm. The colors (blue, yellow, red) of the field strength represent  $0, 2, 5 \times 10^7 \text{V/m}$ , respectively.

#### III. RESULTS

Figures 2 and 3 show the computed optical and electric fields for p-doped-slot waveguides (doping concentration  $1.0 \times 10^{18}/\mathrm{cm}^3$ ) with a size of  $h=w=300\mathrm{nm}$ . We can see evanescent optical and electric field modes in LiNbO3 just under the slot gap, where the top and down layers in Fig. 1 were flipped upside down, and the Si fin structure in Fig. 1 was replaced with a uniform structure with a low refractive index for calculation simplicity. Varying h, we observed that at h<140 nm, the optical evanescent mode turned into a perfectly-leaky mode in LiNbO3, thus setting h=200 nm in what follows. The voltage  $V_{\rm op}$  applied to the slot gap in Fig. 3 was tentatively set at 5V, but this could be reduced to 1V, while the electric-field pattern is almost unchanged (except for its amplitude).

As the slot gap size d decreases, the spread and intensity of the optical field in LiNbO<sub>3</sub> become small, as shown in Fig. 2, although the electric field in Fig. 3 becomes strong because of  $E_z = V_{\rm op}/d$ . Thus there would be an appropriate d so that it could give the maximum overlap integral between the optical and electric fields (or the maximum modulator performance), which is actually realized at d = 50 nm. In this situation, we plotted the half-wavelength voltage  $V_{\pi}$  as a function of the modulator length L (see Fig. 4), where free-carrier optical loss was taken into account. The inset of Fig. 4 shows the logarithmic plot of  $V_{\pi}$  and L, which exhibits linearity, thus providing  $V_{\pi} = A/L$ , where  $A=416 \text{V} \cdot \mu \text{m}$ . This means that if we take  $V_{\pi}=1 \text{V}$ , then  $L=416\mu\mathrm{m}$  (this small L allows us to use lumped constant circuits, excluding travelling-type resistors). If we change the unit  $V \cdot \mu m$  to  $V \cdot cm$ , then we have

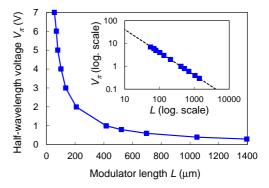


Fig. 4 The half-wavelength voltage  $V_\pi$  vs modulator length L. The inset shows the logarithmic plot of  $V_\pi$  and L.

 $V_\pi \cdot L = 4.16 \times 10^{-2} \mathrm{V} \cdot \mathrm{cm}$ , which is a 1/240 smaller value than that of the conventional LiNbO<sub>3</sub> modulator. We also computed  $V_\pi \cdot L$  of a LiNbO<sub>3</sub>/Si-hybrid modulator of a standard waveguide without a slot, and obtained  $V_\pi \cdot L = 11.1 \mathrm{V} \cdot \mathrm{cm}$  as a structure-optimized value, which is a comparable value to the conventional LiNbO<sub>3</sub> modulator. In comparison with them, we could confirm the effectiveness of using the doped-Si slot waveguide in the LiNbO<sub>3</sub>/Si-hybrid modulator.

#### IV. SUMMARY

We have examined the performance of a LiNbO $_3$ /Si-hybrid E/O modulator with a doped-Si slot waveguide. We have confirmed an excellent performance, i.e., an improvement of two orders of magnitude in  $V_\pi L$ , when compared with that of the conventional LiNbO $_3$  modulator and the LiNbO $_3$ /Si-hybrid modulator with a standard waveguide.

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